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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

Toshifumi NAGAIWA et al.

SERIAL NO.: 09/840,178

FILED: April 24, 2001

FOR: WORKTABLE DEVICE AND
PLASMA PROCESSING APPARATUS
FOR SEMICONDUCTOR PROCESS

:

: GROUP ART UNIT: 1763

:

: EXAMINER: Ram N. KACKAR

AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Responsive to the Office Action dated February 25, 2003, please amend the above-identified application as indicated in the attached pages:

Amendments to the claims are reflected in the listing of claims which begins on page 2 of this amendment.

Remarks/Arguments begin on page 8 of this amendment.